



Attorneys Docket No.: 4935-2A/ETC I/METAL/JB1

Patent

2829

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of:

Steven Verhaverbeke et al.)
U.S. Serial No: 09/945,454)
Filed: August 31, 2001)
For: A METHOD AND APPARATUS FOR
PROCESSING A WAFER)

Examiner: Kilday, Lisa A
Art Unit: 2829

FIRST CLASS CERTIFICATE OF MAILING
(37 c.f.r. § 1.8(a))

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage in an envelope addressed to the Commissioner of Patents and Trademarks, Washington, D.C. 20231 on Teresa Edward

September 27, 2002

Date

Commissioner of
Patents and Trademarks
Washington, D.C. 20231

RESPONSE TO ELECTION REQUIREMENT

Sir:

In response to the Election Requirement mailed August 28, 2002, applicant(s) hereby elects to prosecute Group I claims, claims 1-5, 11-25 and 44-51 drawn to a single wafer wet/dry cleaning apparatus. As such, applicant(s) elects to withdraw Group II-V claims, claims 6-10, 26-43 and 52-79 drawn to a non-elected method.

If there are any additional charges, please charge Deposit Account No. 02-2666.

Respectfully submitted,

BLAKELY, SOKOLOFF, TAYLOR & ZAFMAN

Date: 9/27/02

M. A. Bernadicou

Michael A. Bernadicou
Reg. No. 35,934

PATENT COUNSEL
LEGAL AFFAIRS DEPT.
APPLIED MATERIALS, INC.
BOX 450A
SANTA CLARA, CA 95052

#6
10-8-02
RECEIVED
OCT - 1 2002
TECHNOLOGY CENTER 2800
J. Antes